

EV317135699

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/677,478
Filing Date October 2, 2000
Inventor Guy T. Blalock et al.
Assignee Micron Technology, Inc.
Group Art Unit 1765
Examiner L. Vinh
Attorney's Docket No. MI22-1544
Title: Plasma Etching Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

The Examiner's attention is directed to the references listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: 6-30-03By: 

D. Brent Kenady
Reg. No. 40,045

Sheet 1 of 1

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1544		SERIAL NO. 09/677,375	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary.)				APPLICANT Blalock et al.		FILING DATE October 2, 2000	
				GROUP 1765			
U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	6,333,053 B2	03/18/03	Allen, III				
AB	5,366,353	02/09/99	Chen et al.				
AC	5,365,938	02/02/99	Peters et al.				
AD	5,343,847	12/01/98	Pu et al.				
AE	5,026,666	06/25/91	Hills et al.				
AF	6,434,327 B1	08/13/02	Greer et al.				
AG							
AH							
AI							
AJ							
AK							
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AL							
AM							
AN							
AO							
AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
AR		Stanley Wolf and Richard Tauber, Silicon Processing for the VLSI Era, Vol. 1, pp 549, 1986.					
AS							
AT							
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							